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Inventor Name Search Result

Your Search was:

Last Name = MITROVIC
First Name = ANDREI

| Application# | Patent | Status | Date Filed | Title | Inventor Name |
|--------------|------------|--------|------------|--|------------------|
| 60458063 | Not Issued | 159 | 03/28/2003 | METHOD AND SYSTEM FOR TEMPERATURE CONTROL OF A SUBSTRATE | MITROVIC, ANDREI |
| 60414348 | Not Issued | 159 | 09/30/2002 | APPARATUS AND METHOD FOR USE OF OPTICAL SYSTEM WITH A PLASMA PROCESSING SYSTEM | MITROVIC, ANDREI |
| 60367216 | Not Issued | 159 | 03/28/2002 | APPARATUS AND METHOD FOR USE OF OPTICAL DIAGNOSTIC SYSTEM WITH A PLASMA PROCESSING SYSTEM | MITROVIC, ANDREI |
| 60353534 | Not Issued | 159 | 01/31/2002 | METHOD AND STRUCTURE TO SEGMENT RF COUPLING TO ELECTRODE | MITROVIC, ANDREI |
| 60352546 | Not Issued | 159 | 01/31/2002 | METHOD AND APPARATUS FOR DETERMINATION AND CONTROL OF PLASMA STATE | MITROVIC, ANDREI |
| 60330722 | Not Issued | 159 | 10/31/2001 | APPLIED PLASMA DUCT SYSTEM | MITROVIC, ANDREI |
| 60318828 | Not Issued | 159 | 09/14/2001 | PLASMA REACTOR COIL MAGNET SYSTEM | MITROVIC, ANDREI |
| 60308447 | Not Issued | 159 | 07/30/2001 | PLASMA CHAMBER WALL SEGMENT TEMPERATURE CONTROL | MITROVIC, ANDREI |
| 60304133 | Not Issued | 159 | 06/29/2001 | METHOD OF AND APPARATUS FOR MEASURING AND CONTROLLING WAFER CHUCK TEMPERATURE USING ULTRASONIC TOMOGRAPHY | MITROVIC, ANDREI |
| 60288877 | Not Issued | 159 | 06/19/2001 | CLOSED-DRAFT HALL EFFECT PLASMA VACUUM PUMP FOR PROCESS REACTORS | MITROVIC, ANDREI |
| 60286145 | Not Issued | 159 | 06/07/2001 | APPARATUS AND METHOD FOR DETERMINING CLAMPING STATUS OF SEMICONDUCTOR WAFER | MITROVIC, ANDREI |
| 60272722 | Not Issued | 159 | 03/30/2001 | OPTICAL SYSTEM AND METHOD FOR PLASMA OPTICAL EMISSION ANALYSIS | MITROVIC, ANDREI |
| 60272454 | Not Issued | 159 | 03/02/2001 | APPARATUS AND METHOD OF IMPROVING CAPACITIVELY COUPLED RF VOLTAGE PROBE | MITROVIC, ANDREI |
| 60259861 | Not Issued | 159 | 01/08/2001 | ADDITION OF POWER AT SELECTED HARMONICS OF PLASMA PROCESSOR DRIVE FREQUENCY | MITROVIC, ANDREI |
| 60242114 | Not Issued | 159 | 10/25/2000 | METHOD OF AND STRUCTURE FOR CONTROLLING ELECTRODE TEMPERATURE | MITROVIC, ANDREI |
| 11083246 | Not Issued | 030 | 03/17/2005 | PLASMA PROCESSING SYSTEM AND METHOD | MITROVIC, ANDREI |
| 10293112 | Not Issued | 030 | 11/23/2004 | METHOD OF AND APPARATUS FOR MEASURING AND CONTROLLING SUBSTRATE HOLDER TEMPERATURE USING ULTRASONIC TOMOGRAPHY | MITROVIC, ANDREI |

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|----------|------------|-----|------------|--|------------------|
| 10672346 | Not Issued | 041 | 01/30/2004 | METHOD AND APPARATUS FOR DETERMINING CHEMISTRY OF PARTS RESIDUAL CONTAMINATION | MITROVIC, ANDREI |
| 10673321 | Not Issued | 041 | 09/30/2003 | METHOD AND APPARATUS FOR DETERMINING PLASMA IMPEDANCE | MITROVIC, ANDREI |
| 10673138 | Not Issued | 030 | 09/30/2003 | SYSTEM AND METHOD FOR USING FIRST PRINCIPLES SIMULATION TO FACILITATE A SEMICONDUCTOR MANUFACTURING PROCESS | MITROVIC, ANDREI |
| 10612824 | Not Issued | 150 | 07/03/2003 | ADDITION OF POWER AT SELECTED HARMONICS OF PLASMA PROCESSOR DRIVE FREQUENCY | MITROVIC, ANDREI |
| 10478692 | Not Issued | 071 | 12/08/2003 | APPARATUS AND METHOD FOR DETERMINING CLAMPING STATUS OF SEMICONDUCTOR WAFER | MITROVIC, ANDREI |
| 10469523 | Not Issued | 094 | 02/26/2004 | APPARATUS AND METHOD OF IMPROVING IMPEDANCE MATCHING BETWEEN AN RF SIGNAL AND A MULTI-SEGMENTED ELECTRODE | MITROVIC, ANDREI |
| 10399981 | Not Issued | 071 | 04/24/2003 | METHOD OF AND STRUCTURE FOR CONTROLLING ELECTRODE TEMPERATURE | MITROVIC, ANDREI |
| 10388549 | Not Issued | 030 | 03/17/2003 | APPARATUS AND METHOD FOR USE OF OPTICAL DIAGNOSTIC SYSTEM WITH A PLASMA PROCESSING SYSTEM | MITROVIC, ANDREI |
| 10359557 | Not Issued | 061 | 02/07/2003 | METHOD AND APPARATUS FOR IMPROVED PLASMA PROCESSING UNIFORMITY | MITROVIC, ANDREI |
| 10351173 | Not Issued | 150 | 01/31/2003 | METHOD AND APPARATUS FOR DETERMINATION AND CONTROL OF PLASMA STATE | MITROVIC, ANDREI |
| 10189425 | Not Issued | 150 | 07/08/2002 | SEGMENTED ELECTRODE APPARATUS AND METHOD FOR PLASMA PROCESSING | MITROVIC, ANDREI |
| 10183360 | Not Issued | 161 | 06/28/2002 | METHOD OF AND APPARATUS FOR MEASURING AND CONTROLLING SUBSTRATE HOLDER TEMPERATURE USING ULTRASONIC TOMOGRAPHY | MITROVIC, ANDREI |
| 10096932 | Not Issued | 150 | 03/14/2002 | OPTICAL SYSTEM AND METHOD FOR PLASMA OPTICAL EMISSION ANALYSIS | MITROVIC, ANDREI |

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| Application# | Patent | Status | Date Filed | Title | Inventor Name |
|--------------|------------|--------|------------|--|---------------------|
| 60458442 | Not Issued | 159 | 03/31/2003 | PLASMA PROCESSING SYSTEM AND METHOD | MITROVIC, ANDREI S. |
| 60457389 | Not Issued | 159 | 03/27/2003 | METHOD AND SYSTEM FOR MONITORING RF IMPEDANCE TO DETERMINE CONDITIONS OF A WATER ON AN ELECTROSTATIC CHUCK | MITROVIC, ANDREI S. |
| 60439962 | Not Issued | 159 | 11/26/2002 | PLASMA PROCESSING SYSTEM AND METHOD | MITROVIC, ANDREI S. |
| 60413432 | Not Issued | 159 | 09/30/2002 | PLASMA PROCESSING SYSTEM AND METHOD | MITROVIC, ANDREI S. |
| 60411122 | Not Issued | 159 | 12/31/2001 | LINEAR INDUCTIVE PLASMA PUMP FOR PROCESS REACTORS | MITROVIC, ANDREI S. |
| 60368912 | Not Issued | 159 | 02/16/2001 | METHOD AND APPARATUS FOR TRANSPERING HEAT FROM A SUBSTRATE TO A CHUCK | MITROVIC, ANDREI S. |
| 60231132 | Not Issued | 159 | 11/28/2000 | METHOD AND APPARATUS FOR 2-D SPATIALLY RESOLVED OPTICAL EMISSION AND ABSORPTION SPECTROSCOPY | MITROVIC, ANDREI S. |
| 60223834 | Not Issued | 159 | 08/08/2000 | METHOD AND APPARATUS FOR IMPROVED PLASMA PROCESSING UNIFORMITY | MITROVIC, ANDREI S. |
| 60182188 | Not Issued | 159 | 02/14/2000 | DEVICE AND METHOD FOR COUPLING TWO CIRCUIT COMPONENTS WHICH HAVE DIFFERENT IMPEDANCES | MITROVIC, ANDREI S. |
| 60182187 | Not Issued | 159 | 02/14/2000 | METHOD AND DEVICE FOR ATTENUATING HARMONICS IN SEMICONDUCTOR PLASMA PROCESSING SYSTEMS | MITROVIC, ANDREI S. |
| 60173284 | Not Issued | 159 | 01/10/2000 | SEGMENTED ELECTRODE APPARATUS AND METHOD FOR PLASMA PROCESSING | MITROVIC, ANDREI S. |
| 11082222 | Not Issued | 030 | 03/17/2003 | APPARATUS AND METHOD FOR USE OF OPTICAL SYSTEM WITH A PLASMA PROCESSING SYSTEM | MITROVIC, ANDREI S. |
| 11065065 | Not Issued | 030 | 02/25/2003 | CHUCK PEDESTAL SHIELD | MITROVIC, ANDREI S. |
| 10812075 | Not Issued | 095 | 03/31/2004 | LOW REFLECTION MICROWAVE WINDOW | MITROVIC, ANDREI S. |
| 10811912 | Not Issued | 030 | 03/30/2004 | HONEYCOMB OPTICAL WINDOW DEPOSITION SHIELD AND METHOD FOR A PLASMA PROCESSING SYSTEM | MITROVIC, ANDREI S. |
| 10807432 | Not Issued | 030 | 03/24/2004 | METHOD AND SYSTEM FOR MONITORING RF IMPEDANCE TO DETERMINE CONDITIONS OF A WATER ON AN ELECTROSTATIC CHUCK | MITROVIC, ANDREI S. |
| 10793815 | Not Issued | 030 | 03/08/2004 | PLASMA REACTOR COIL MAGNET | MITROVIC, ANDREI S. |
| 10792323 | Not Issued | 030 | 03/05/2004 | METHOD AND APPARATUS FOR IMPROVED PLASMA PROCESSING UNIFORMITY | MITROVIC, ANDREI S. |
| 10767347 | Not Issued | 041 | 01/20/2004 | METHOD AND SYSTEM FOR MONITORING | MITROVIC, ANDREI S. |

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| 10765445 | Not Issued | 020 | 01/28/2004 | PLASMA CHAMBER WALL SEGMENT TEMPERATURE CONTROL | MITROVIC, ANDREI S. |
| 10729948 | Not Issued | 150 | 12/19/2003 | CLOSED-DRIFT HALL EFFECT PLASMA VACUUM PUMP FOR PROCESS REACTORS | MITROVIC, ANDREI S. |
| 10720052 | Not Issued | 020 | 11/25/2003 | PLASMA PROCESSING SYSTEM AND METHOD | MITROVIC, ANDREI S. |
| 10673583 | Not Issued | 030 | 09/30/2003 | SYSTEM AND METHOD FOR USING FIRST-PRINCIPLES SIMULATION TO PROVIDE A SEMICONDUCTOR MANUFACTURING PROCESS | MITROVIC, ANDREI S. |
| 10673501 | Not Issued | 030 | 09/30/2003 | SYSTEM AND METHOD FOR USING FIRST-PRINCIPLES SIMULATION TO CHARACTERIZE A SEMICONDUCTOR MANUFACTURING PROCESS | MITROVIC, ANDREI S. |
| 10659510 | Not Issued | 061 | 08/13/2003 | METHOD AND APPARATUS FOR TRANSPERING HEAT FROM A SUBSTRATE TO A CHUCK | MITROVIC, ANDREI S. |
| 10611902 | Not Issued | 161 | 07/03/2003 | CAPACITIVELY COUPLED RF VOLTAGE PROBE | MITROVIC, ANDREI S. |
| 10432713 | Not Issued | 094 | 05/27/2003 | METHOD AND APPARATUS FOR 2-D SPATIALLY RESOLVED OPTICAL EMISSION AND ABSORPTION SPECTROSCOPY | MITROVIC, ANDREI S. |
| 10357454 | Not Issued | 095 | 02/04/2003 | CONTROL METHOD FOR SEGMENTED ELECTRODE APPARATUS AND METHOD FOR PLASMA PROCESSING | MITROVIC, ANDREI S. |
| 10355202 | Not Issued | 150 | 01/31/2003 | METHOD AND STRUCTURE TO SEGMENT RF COUPLING TO SILICON ELECTRODE | MITROVIC, ANDREI S. |
| 10335828 | Not Issued | 150 | 12/23/2002 | LINEAR INDUCTIVE PLASMA PUMP FOR PROCESS REACTORS | MITROVIC, ANDREI S. |
| 10283358 | Not Issued | 150 | 10/30/2002 | APPLIED PLASMA DUCT SYSTEM | MITROVIC, ANDREI S. |
| 10218114 | Not Issued | 150 | 08/14/2002 | DEVICE AND METHOD FOR COUPLING TWO CIRCUIT COMPONENTS WHICH HAVE DIFFERENT IMPEDANCES | MITROVIC, ANDREI S. |
| 10218036 | Not Issued | 150 | 08/14/2002 | METHOD AND DEVICE FOR ATTENUATING HARMONICS IN SEMICONDUCTOR PLASMA PROCESSING SYSTEMS | MITROVIC, ANDREI S. |

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